

<b>Notice of References Cited</b>	Application/Control No. 10/006,704	Applicant(s)/Patent Under Reexamination TRAPP, SHANE J.	
	Examiner Lynette T. Umez-Eronini	Art Unit 1765	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,277,733 B1	08-2001	Smith, Patricia B.	438/636
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	JP 54054578	04-1979	Japan	Fumio et al.	H01L 21/302
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Fumio et al., Gas Plasma Etching Method, April 28, 1979, English Abstract of JP 54054578, 2 pages.
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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